

## TECHNICAL SPEC FOR Deposition/Etch tool

System Model: **AMAT Centura Ultima+ HDP-CVD**

Process: **HDP-CVD**

Wafer size: **6"**

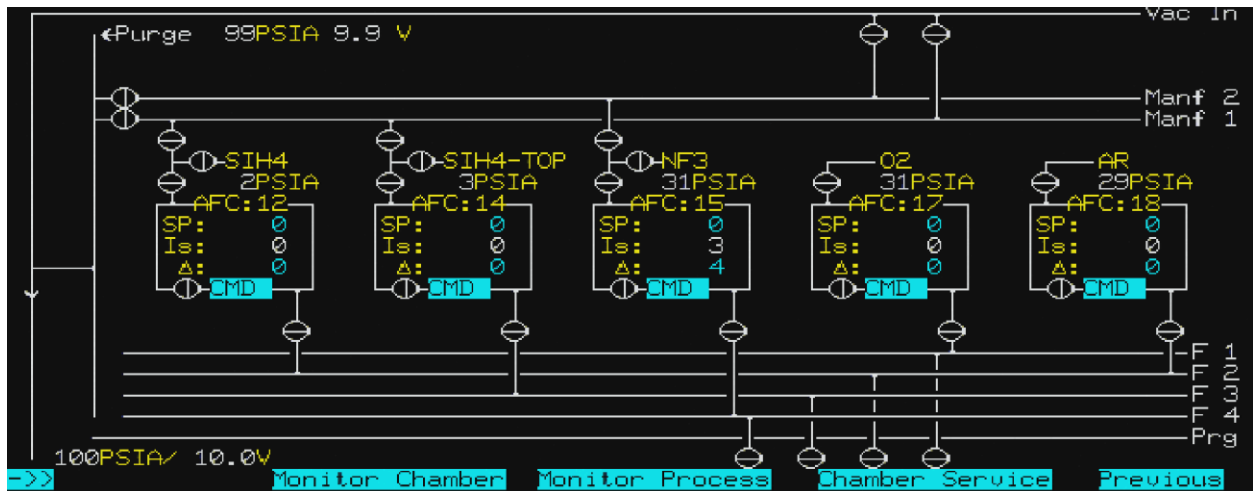
Wafer type: **JMF**

Valve type: **HVA 21251-1003Z-001 gate valve**

Wide/Narrow body: **Narrow body**

Frame: **Chamber A and B – MS Cool Down (E) and Orienter (F)**

Gas and process configuration **identical for all process chambers**



|          |    |               |
|----------|----|---------------|
| SiH4     | // | MFC 200 sccm  |
| SiH4-Top | // | MFC 20 sccm   |
| NF3      | // | MFC 3000 sccm |
| O2       | // | MFC 400 sccm  |
| Ar       | // | MFC 300 sccm  |

**Vintage:** Yes

**Missing/defective parts:** **None**

**Photos to Collect**

- All 4 sides
- Robot
- Loader
- Gas lines
- Gas box
- Close up from each chamber
- Turbos and Pumps on each process module
- Bottom of each side (there are VGA's, and a number of other cards on the bottom of the sides of the tool)
- Controllers
- Electrical cabinets
- AC Rack
- Gas in/outlets
- Electrical in/outlets
- Chiller
- Serial plates of all chambers
- Serial plate of Mainframe
- Serial plate of each pump
- Spare parts, manuals (if any)